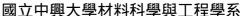


國立中興大學材料科學與工程學系 (Department of Materials Science and Engineering, National Chung Hsing University)

教學大綱(Syllabus)-研究所

系務會議通過修訂日期:2007/9/12

| 課程編碼 (course no.) | M024 | | | 學分 (credits) | 3 | | | |
|--|---|--------------|-----------|-----------------|------------------------|--|--|--|
| 課程名稱 | (中) 電漿製程技術 (Eng.) Plasma Processing Technology | | | | | | | |
| (course name) | | | | | | | | |
| 開課系所班級 | 材料科學與工 | 程學系碩士: | 班1年級 | 授課教師 | 施漢章教授 | | | |
| (dept. & year) | (Dept. of Mat. | Sci. & Engr. | .,Master) | (teacher) | (Prof. Han-Chang Shih) | | | |
| 課程類別 | 選修 | 授課語言 | 中文 | 開課學期 | 上學期 | | | |
| (course type) | (Elective) | (language) | (Chinese) | (semester) | (Fall) | | | |
| 課程簡述 (course description) | (中) 本課程的目的在於讓學生了解電漿技術的基本原理,包括電漿生成原理、內部構造、基礎電漿理論、電漿製程於各種產業上之應用。此課程為以課堂的授課為主,並推廣至柰米科技製程上的應用,讓學生能更加了解電漿製程的多功能應用性。 (Eng.) The objective of this curriculum goal lies in lets students understand the basic principle of plasma processing technology, including plasma theorem、plasma structures、basic plasma theory、 applications in the industry. It is a lecture-oriented course, and | | | | | | | |
| | promotion to nano technology and processing, enable the student even more to understand the multi-purpose application for the plasma processing technology. (中) | | | | | | | |
| 課程目標 (course | 了解電漿製程技術的基本原理 了解電漿製成的基礎理論 了解不同類型電漿產生儀器與應用 了解電漿製程於傳統產業的應用 了解電漿製程於高科技光電產業的應用 了解電漿製程於奈米科技上的應用 了解電漿製程於生物醫學科技產業的應用 | | | | | | | |
| objectives) (Eng.) 1. Plasma processing technology 2. Basic plasma theory 3. Including plasma structures 4. Plasma processes for surface Modification 5. Plasma in the flat panel display industry 6. Plasma in the multi-purpose application 7. Plasma for biology processing | | | | | | | | |
| 先修課程(prerequisites) | | | | | | | | |
| 課程編碼 | 課程名稱 | | | | 念、原理與技能 | | | |
| (course no.) | (course nam | e) | (rela | ation to the cu | rrent course) | | | |
| | | | | | | | | |
| | | | | | | | | |





國立中興大學材料科學與工程學系 (Department of Materials Science and Engineering, National Chung Hsing University)

| 教學模式 (teaching methodology) | 模式 (methodology) | 講授 (teaching) | 討論/報告 (discussion & report) | 實驗/參訪 (exp./fab visit) | 遠距/網路教學 (remote/web teaching) | 合計 (sum) |
|-----------------------------------|---------------------------|------------------|-----------------------------------|---------------------------|-------------------------------------|-------------|
| | 學分分配 (credit distrib.) | 3 | 4 | | | 3 |
| | 授課時數分配 (hour distrib.) | 3 | 4 | | | 3 |



(Department of Materials Science and Engineering, National Chung Hsing University)

| 授課進度與內容(週次、單元名稱與內容、習作/考試進度、備註) (course content and homework/tests schedule) | | | | | | |
|--|---|------------------------------------|----------------|--|--|--|
| 週次 (week) | 單元名稱與內容 (subject and content) | 習作/考試進度 (homework and tests) | 備註 (remark) | | | |
| 01 | Materials processing | | | | | |
| 02 | Plasma, Sheaths, particle-in-cell (PIC) and Discharges | | | | | |
| 03 | The Maxwell distribution | Homework # 1 | | | | |
| 04 | Debye length — plasma 之另一重要參數 | | | | | |
| 05 | Thermal plasmas and Cold plasma | | | | | |
| 06 | Radio frequency discharge (RF 放電) 電子迴旋共振 (ECR) plasma and Plasma oscillations | Homework # 2 | | | | |
| 07 | 電漿化學、Homogeneous Reactions and Hetrogeneous Reactions | | | | | |
| 08 | Plasma Surface Interactions | | | | | |
| 09 | 歐傑電子 (Auger e-) | Homework # 3 | | | | |
| 10 | 離子和電子誘發的化學反應 | | | | | |
| 11 | Energy transfer and Effect on Film Growth | | | | | |
| 12 | Plasma in the flat panel display industry | | | | | |
| 13 | Plasma reacto | | | | | |
| 14 | Electrodeless discharges (無電極放電) | | | | | |
| 15 | Langnuir probes 或 electrostatic probes 靜電探針 | | | | | |
| 16 | | | | | | |
| 17 | StructureSynthesis, Applications | | | | | |
| 18 | Atomistic Modelling | Final Examination | | | | |

(evaluation)

- (1) Homework assignment: 20%
- (2) Midterm Examination 40%
- (3) Final Examination 40%

作業 (Homework):

作業共 4 次,目的在評估學生對課堂講授資料以及同分組報告資料的了解程度,並且培養同學平日課後複習的習慣以及思考問題的能力。

期中與期末考試 (Midterm and Final Examination):

期中與期末考試測驗各一次,目的在於評估學生對於電漿製程授課的了解度。

國立中興大學材料科學與工程學系



(Department of Materials Science and Engineering, National Chung Hsing University)

教科書(書名、作者、書局、代理商、說明)

(textbook)

- 1、Cold Plasma in Materials Fabrication, Alfred Grill, IEEE Press, New York, 1994.
- 2、 Principles of plasma Discharges and Materials Processing, M. A. Lieberman and A. J. Lichtenberg, John Wiley, New York, 1994.

參考書目(書名、作者、書局、代理商、說明

(other references)

1、"Handbook of plasma Processing Technology", edited by Stephen M. Rossnagel, Jerome J. Cuomo and William D. Westwood, Noyes Publications, 1989.2、

- 2, "Glow Discharge Processes", Brian Chapman, Wiley, New York, 1980.3,
- 3, "Microwaves", A. J. Baden Fuller, Pergamon Press, 1990.

課程教材(教師個人網址請列在本校內之網址。)

(teaching aids & teacher's website)

1. Power point files.

與學系教育目標之關聯性(材料系)

(relation to educational objective of materials engineering department)

1. 提供材料性質、製程與應用及跨領域知識與訓練

To provide interdisciplinary know-how and training on materials properties, processing, and applications

2. 培育具獨立思考、創新與實作能力之材料科技人才

To train materials technology students for independent thinking, innovation, and practical skills

3. 培養團隊合作精神與溝通協調整合能力

To cultivate the spirit of teamwork and the capacity of integrated cooperation

4. 建立多元價值與國際觀

To inculcate multifarious values and cosmopolitan worldview

5. 強化綠色材料科技教育

To implement educational programs in eco-materials technology

與學系教育核心能力之關聯性(材料系)

(relation to educational core abilities for materials engineering department)

(A) 特定材料之專業知識

Specialized knowledge in Materials science and Engineering

(B) 策劃及執行專題研究之能力

Ability to plan and execute a research project

(C) 撰寫專業論文之能力

Ability to write journal articles

(D) 創新思考及獨立解決問題之能力

Ability to do innovative thinking and independent problem solving

(E) 跨領域協調整合之能力

Ability to work in an interdisciplinary setting

(F) 國際觀及綠色材料意識

A fine international scope and general concept of eco-material

(G) 領導、管理及規劃之能力

Ability in leadership, management, and organization

(H) 終身自我學習成長之能力

Ability for life-long learning

(I) 學術專業倫理

Professional ethics in Science and Engineering



課程內涵達成學系【教育目標】比對資料

| | 教育目標 | | | | | | |
|---|-------------------------|-------------------------|-------|-------|-------|--|--|
| | 目標一 | 目標二 | 目標三 | 目標四 | 目標五 | | |
| | 提供材料性 | 培育具獨立 | 培養團隊合 | 建立多元價 | 強調綠色材 | | |
| 授課進度與內容 | 質、製程與應 | 思考、創新與 | 作精神與溝 | 值與國際觀 | 料科技教育 | | |
| | 用及跨領域 | 實作能力之 | 通協調整合 | | | | |
| | 知識與訓練 | 材料科技人 | 能力 | | | | |
| | | オ | | | | | |
| 請勾選關聯性☑ | $\overline{\mathbf{Q}}$ | $\overline{\mathbf{A}}$ | | | | | |
| Materials processing | 0 | 0 | 0 | 1 | 0 | | |
| Plasma, Sheaths, particle-in-cell | 1 | 0 | 0 | 0 | 0 | | |
| (PIC) and Discharges | 1 | O | U | U | U | | |
| The Maxwell distribution | 1 | 0 | 0 | 0 | 0 | | |
| Debye length — plasma 之另一重要參數 | 1 | 0 | 0 | 0 | 0 | | |
| Thermal plasmas and | 1 | 0 | 0 | 0 | 0 | | |
| Cold plasma | • | Ŭ | Ů | Ů | | | |
| Radio frequency discharge (RF 放電) | | | | | | | |
| 、電子迴旋共振(ECR) plasma and Plasma | 1 | 0 | 0 | 0 | 0 | | |
| oscillations | | | | | | | |
| 電漿化學、Homogeneous Reactions and | 1 | 0 | 0 | 0 | 0 | | |
| Hetrogeneous Reactions | 1 | U | U | | U | | |
| Plasma Surface Interactions | 1 | 0 | 0 | 0 | 0 | | |
| 歐傑電子 (Auger e-) | 1 | 1 | 0 | 0 | 0 | | |
| 離子和電子誘發的化學反應 | 1 | 0 | 0 | 0 | 0 | | |
| Energy transfer and Effect on Film Growth | 1 | 0 | 0 | 0 | 0 | | |
| Plasma in the flat panel display industry | 1 | 0 | 0 | 0 | 0 | | |
| Plasma reacto | 1 | 0 | 0 | 0 | 0 | | |
| Electrodeless discharges (無電極放電) | 1 | 0 | 0 | 0 | 0 | | |
| Langnuir probes 或 electrostatic probes | 1 | 1 | 0 | 0 | 0 | | |
| 靜電探針 | 1 | 1 | U | U | 0 | | |
| StructureSynthesis, Applications | 1 | 0 | 0 | 0 | 0 | | |
| Atomistic Modelling | | 1 | 0 | 0 | 0 | | |
| 總計(%) | 88(%) | 17(%) | 0(%) | 6(%) | 0(%) | | |

註: 1. 所有必修課均須填寫此表。

2. 矩陣中請填入關聯性; 1表示相關,0表示無相關。

3. 學系教育目標項次請依據表1填寫。



(Department of Materials Science and Engineering, National Chung Hsing University)

課程內涵達成學系【核心能力】比對資料(研究所)

| | 核心能力 | | | | | | | | | |
|----------------------------------|------|-----|-----|----------|-----|----------|------|----------|------|--|
| | A | В | С | D | Е | F | G | Н | I | |
| 授課進度與內容 | 特定材 | 策劃及 | 撰寫專 | 創新思 | 跨領域 | 國際觀 | 領導、管 | 終身自 | 學術專 | |
| 技 际進及契内谷 | 料之專 | 執行專 | 業論文 | 考及獨 | 協調整 | 及綠色 | 理及規 | 我學習 | 業倫理 | |
| | 業知識 | 題研究 | 之能力 | 立解 | 合之能 | 材料意 | 劃之能 | 成長之 | | |
| | | 之能力 | | 決問題 之能力 | カ | 戠 | カ | 能力 | | |
| 請勾選關聯性団 | Ø | | Ø | Z 18273 | | | | | Ø | |
| Materials processing | 1 | 0 | 0 | 0 | 0 | 0 | 0 | 0 | 1 | |
| Plasma, Sheaths, | | | | | | | | | | |
| particle-in-cell | 1 | 0 | 0 | 0 | 0 | 0 | 0 | 0 | 1 | |
| (PIC) and Discharges | | | | | | | | | | |
| The Maxwell distribution | 1 | 0 | 0 | 1 | 0 | 0 | 0 | 0 | 1 | |
| Debye length — plasma 之另 | 1 | 0 | 0 | 0 | 0 | 0 | 0 | 0 | 1 | |
| 一重要參數 | 1 | 0 | 0 | 0 | 0 | 0 | 0 | 0 | 1 | |
| Thermal plasmas and | 1 | 0 | 0 | 1 | 0 | 0 | 0 | 0 | 1 | |
| Cold plasma | 1 | U | U | 1 | U | 0 | U | U | 1 | |
| Radio frequency discharge(RF | | | | | | | | | | |
| 放電) 電子迴旋共振(ECR) | 1 | 0 | 0 | 0 | 0 | 0 | 0 | 0 | 1 | |
| plasma and Plasma oscillations | | | | | | | | | | |
| 電漿化學、Homogeneous | | | | | | | | | | |
| Reactions and Hetrogeneous | 1 | 0 | 0 | 1 | 0 | 0 | 0 | 0 | 1 | |
| Reactions | | | | | | | | | | |
| Plasma Surface Interactions | 1 | 1 | 1 | 0 | 0 | 0 | 0 | 0 | 1 | |
| 歐傑電子 (Auger e-) | 1 | 0 | 0 | 0 | 0 | 0 | 0 | 0 | 1 | |
| 離子和電子誘發的化學反應 | 1 | 0 | 0 | 0 | 0 | 0 | 0 | 0 | 1 | |
| Energy transfer and Effect on | 1 | 0 | 0 | 0 | 0 | 0 | 0 | 0 | 1 | |
| Film Growth | 1 | Ů | Ů | V | Ů | Ů | Ů | Ů | 1 | |
| Plasma in the flat panel display | 1 | 0 | 0 | 1 | 0 | 0 | 0 | 0 | 1 | |
| industry | | | | _ | | | | | | |
| Plasma reacto | 1 | 0 | 0 | 0 | 0 | 0 | 0 | 0 | 1 | |
| Electrodeless discharges (無電 | 1 | 1 | 1 | 0 | 0 | 0 | 0 | 0 | 1 | |
| 極放電) | 1 | 1 | 1 | U | U | U | U | U | 1 | |
| Langnuir probes 或 | 1 | 0 | 0 | 1 | 0 | 0 | 0 | 0 | 1 | |
| electrostatic probes 靜電探針 | 1 | U | U | 1 | U | U | U | U | 1 | |
| Structure Synthesis, | 1 | 1 | 1 | 0 | 0 | 0 | 0 | 0 | 1 | |
| Applications | 1 | 1 | 1 | <u> </u> | U | <u> </u> | U | <u> </u> | 1 | |
| 總計(%) | 100% | 18% | 18% | 29% | 0% | 0% | 0% | 0% | 100% | |

註: 1. 所有必修課均須填寫此表。

2. 矩陣中請填入關聯性; 1表示相關,0表示無相關。

3. 學系教育目標項次請依據表1填寫。